

# Communications Microsystems for Spacecraft – Current Research and Future Systems

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# Outline

- Multifunctional Microsystems Applied on Communication Modules
- Current research at ÅSTC
- Front end of S-band module as an example
- Why silicon as a RF/mm-Wave substrate?
- Cross-disciplinary research
- Conclusions



# Multifunctional Microsystem MMS – Applied on Communication Modules

## Traditional RF system

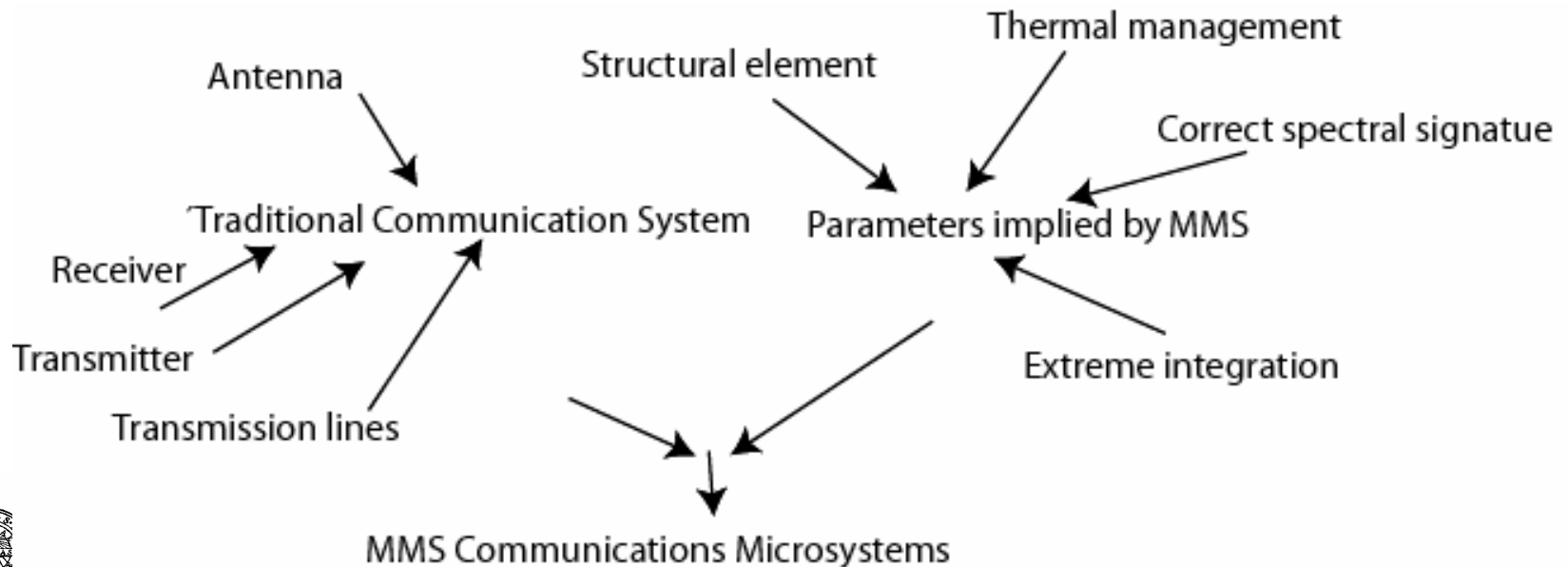
- Separate parts connected together with transmissions lines

## Highly integrated RF modules

- One RF module contains all necessary parts integrated

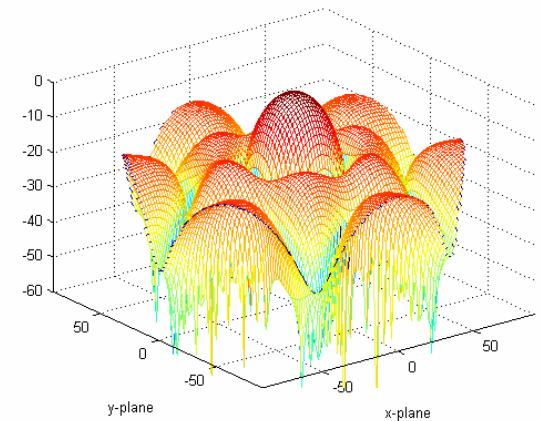
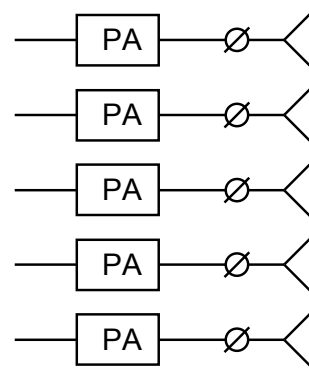
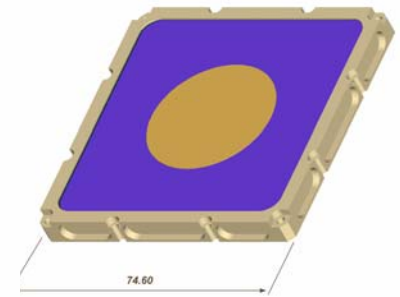
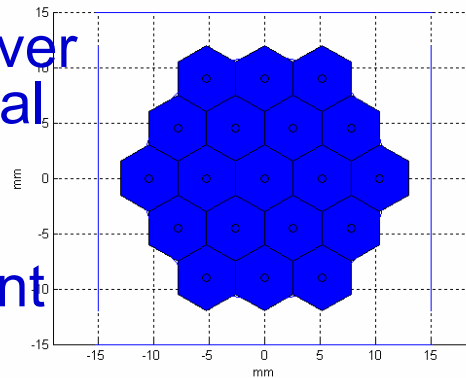
## MMS Applied on RF modules

- Extreme minityzation
- All necessary functions integrated
  - Thermal management
  - Communication module
  - Spectral admittance
  - And so on...



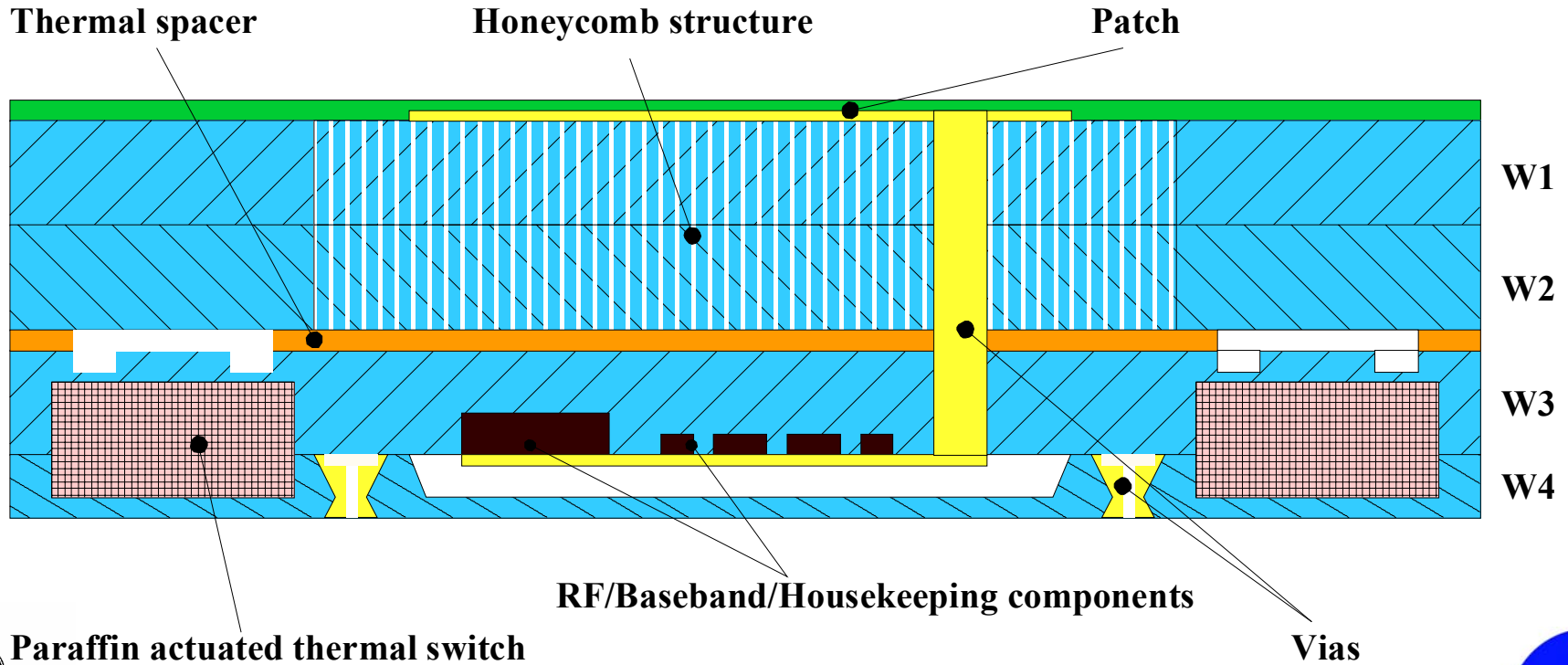
# Current Research at ÅSTC

- S-band Transmitter and Receiver modules with integrated thermal management
- Ka-band phased array with integrated thermal management
  - Transmission lines on membranes
  - RF through vias
  - Phase shifters
- Basic technology
  - Silicon as substrate
  - MST, MEMS
  - MMS



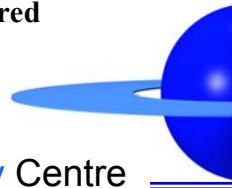
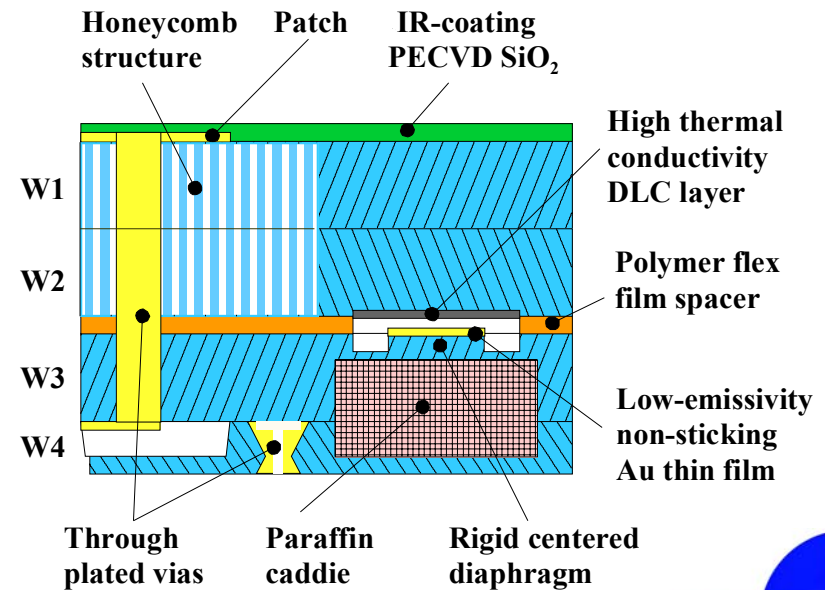
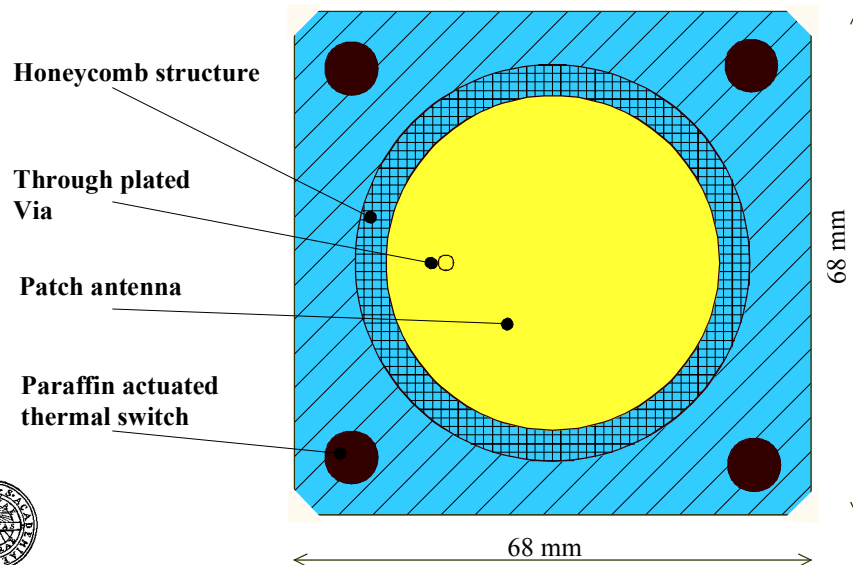
# S-band Transmitter/Receiver with Integrated Thermal Control

The system consists of a 4 wafer bonded silicon wafer stack



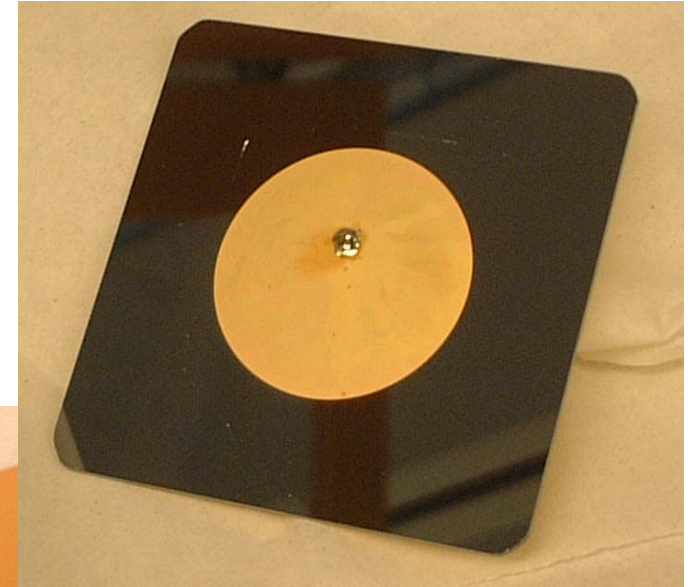
# S-band Transmitter/Receiver with Integrated Thermal Control

- Bulk thinned silicon, thermal coating, active MST heat management
- 20 grams, 68 mm square, 2 mm thickness
- Estimated RF-power 1.5W, Antenna gain 3.6dBi



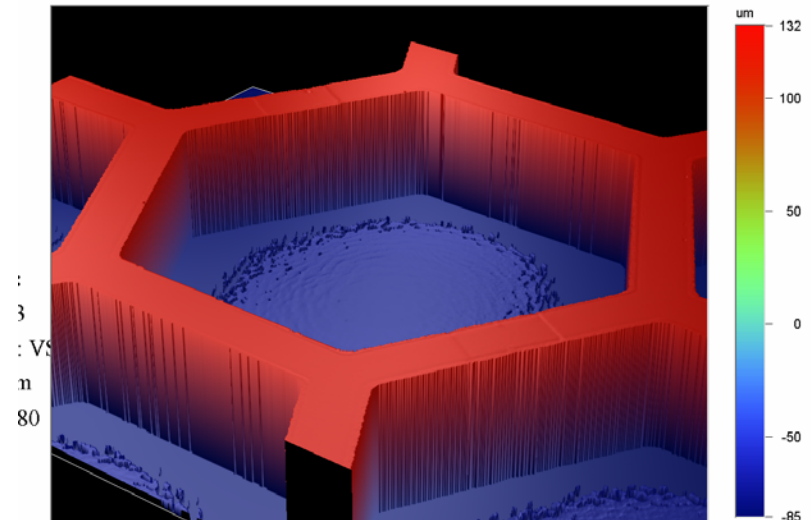
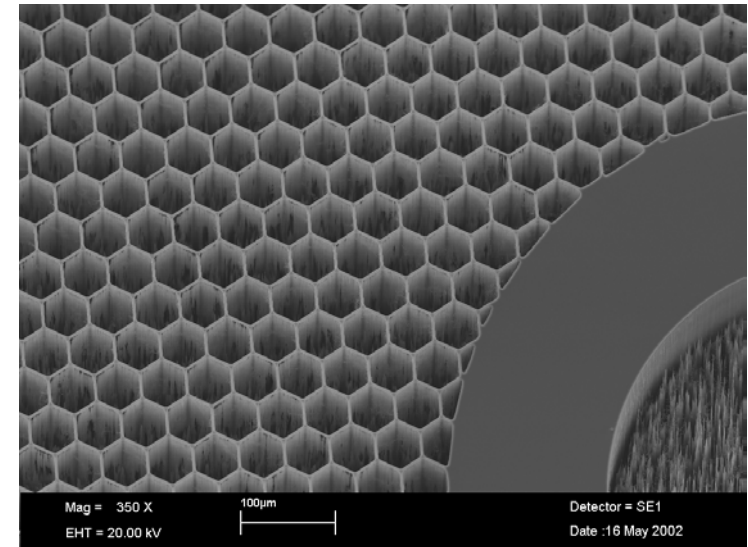
# Bonded top wafers manufactured

- Two bonded silicon wafers (each 525  $\mu\text{m}$  thickness)
- Honeycomb support structure
- Simple SMA contact attachment for preliminary tests



# Thinned Bulk Silicon Structure

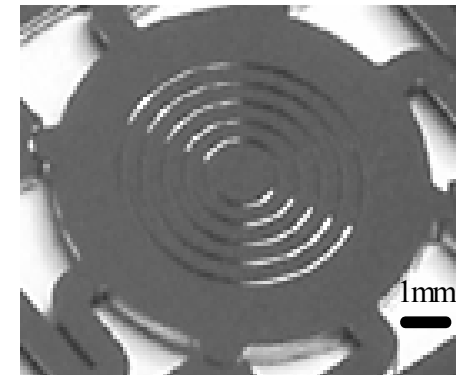
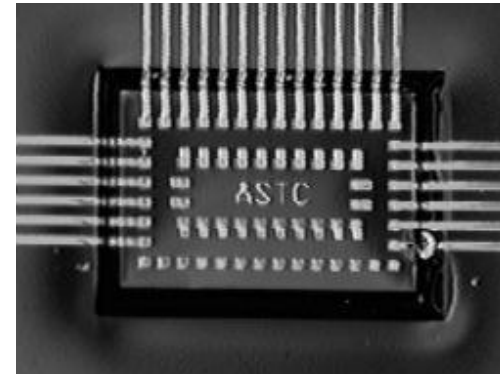
- Reduced losses
- Lower dielectricity constant → more broadband device
- MST process, DRIE etched honeycomb pattern
- Dielectric value reduced from 11.9 to 3.8!





# Integration of actuators and 'chips', or Why silicon?

- Well known micromechanical methods for producing very compact MCM modules using silicon as substrate
- E.g. Thin film connection of chips in etched pits (MCM):
  - Advantageous at high frequencies due to reduced parasitic impedances.
- Easy packaging (Si-Si bonding)
- Actuator integration
  - E.g. Paraffin as actuator in thermal switches in presented S-band module.



# Cross-disciplinary Research

- Materials science
- Materials analysis
- Microwave technology
- Antenna analysis
- Device technology
- FPGA/microcontroller technology for stand alone 'smart' microsystems
- and more...



# Conclusions for future communications microsystems

- Low cost
- High redundancy
- New mission scenarios
- Few interconnects to outside 'world' (spacecraft)



# Thanks for your attention!

- Questions?



Smarter...

Smaller...

Lighter...

Multifunctional...

... are the keywords for  
Communications  
Microsystems  
of the future

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